

WE ARE
THE
PARTNER
FOR CUSTOMIZED WET PROCESS
EQUIPMENT

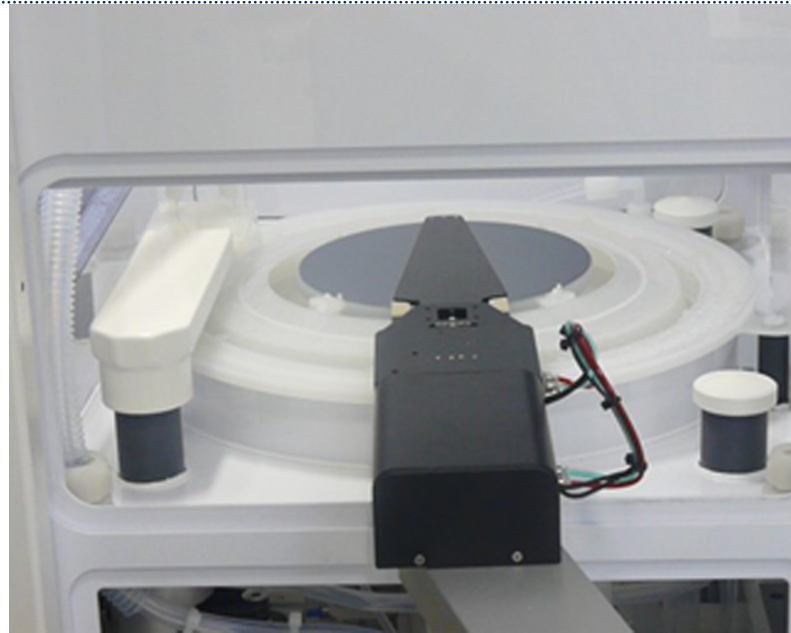
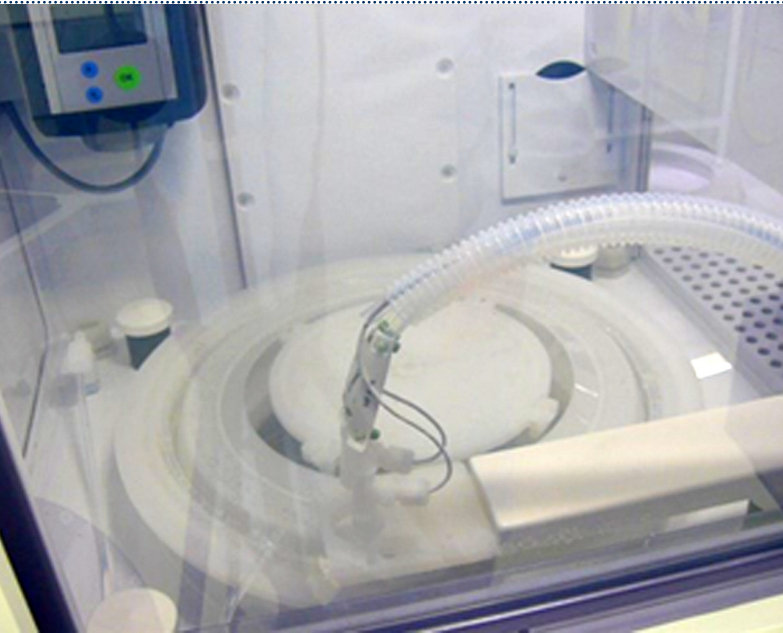


SpinEtcher *SPE 200*

SpinEtcher from SEMI PARTS. Our proved tool for FEOL and BEOL processes.

BENEFITS

- > Up to 5 media in one process bowl
- > Backside protection chuck
- > Low chemical and water consumption
- > Chemical recirculation and recycling
- > Front- and backside handling selectable in the recipe
- > High safety levels for chemicals
- > Easy upgrade to second process bowl
- > Easy to change wafer size
- > Optimized footprint



APPLICATIONS

The SpinEtcher SPE 200 is designed for processes like:

- > Roughness etching
- > Stress relief
- > Polishing
- > Film removal

OPTIONS

- > Thin wafer handling
- > Mini chemical dispense and mixture systems
- > Endpoint detection
- > Concentration monitoring
- > Spiking unit
- > SECS GEM interface
- > SMIF or open carrier handling
- > Wafer ID/Barcode reader
- > Efficient chuck and bowl cleaning system
- > Ionization unit

| TECHNICAL DATA | SpinEtcher SPE 200-I | SpinEtcher SPE 200-II |
|----------------------------------|-----------------------|----------------------------|
| Wafer size | up to 200 mm | up to 200 mm |
| Wafer carrier | SMIF / open carrier | SMIF / open carrier |
| Process bowl | 1 with up to 5 medias | 2 with up to 5 medias each |
| Thin wafer handling | yes | yes |
| Front side and backside handling | yes | yes |
| Dimensions (W x D x H) | 1600 x 1300 x 2000 mm | 2200 x 1300 x 2000 mm |